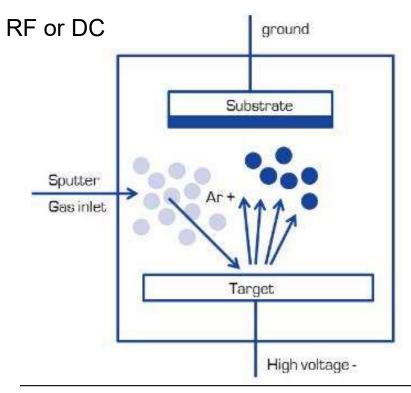
RUTGERS

Sputter tool – Denton Explorer 14

- Depositing Cr, Al, Ag, NiO, ZnO, AZO layers
- Sample Sizes: Pieces 6" wafer
- Target Size: 3 inch
- Base Pressure ~ 2.2x10⁻⁶ Torr
- Pump Time ~ 3 Hours
- Operation Gas Flow ~ Ar, 30sccm





Nanofabrication CORE Facility